

Varun

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/3400452/publications.pdf>

Version: 2024-02-01

10
papers

125
citations

1478505

6
h-index

1372567

10
g-index

10
all docs

10
docs citations

10
times ranked

49
citing authors

#	ARTICLE	IF	CITATIONS
1	PIC Simulation to Analyze Peak Electron Current Generation in a Triggered Pseudospark Discharge-Based Plasma Cathode Electron Source. IEEE Transactions on Electron Devices, 2018, 65, 1542-1549.	3.0	26
2	PIC Simulation of Pseudospark Discharge-Based Plasma Cathode Electron Source for the Generation of High Current Density and Energetic Electron Beam. IEEE Transactions on Electron Devices, 2020, 67, 1793-1796.	3.0	22
3	A Multigap Multiaperture Pseudospark Switch and Its Performance Analysis for High-Voltage Applications. IEEE Transactions on Electron Devices, 2020, 67, 5600-5604.	3.0	18
4	Breakdown Characteristics of Triggered Pseudospark Discharge-Based Multigap Plasma Cathode Electron Source. IEEE Transactions on Electron Devices, 2018, 65, 4607-4613.	3.0	15
5	Experimental and simulation analysis of dielectric barrier discharge based pulsed cold atmospheric pressure plasma jet. Physics of Plasmas, 2020, 27, .	1.9	14
6	Investigation of Electron Beam Generation in Pseudospark Discharge-Based Plasma Cathode Electron Source. IEEE Transactions on Plasma Science, 2018, 46, 2003-2008.	1.3	12
7	Design of Multigap Pseudospark Discharge-Based Plasma Cathode Electron Source at Different Configurations of Electrode Apertures. IEEE Transactions on Electron Devices, 2021, 68, 5799-5806.	3.0	6
8	Analysis of Discharge Characteristics of Cold Atmospheric Pressure Plasma Jet. IEEE Transactions on Plasma Science, 2021, 49, 2799-2805.	1.3	6
9	Impact of Irregular Electrode Apertures in Multigap Pseudospark Discharge Geometries for the Generation of High Density and Energetic Electron Beams. IEEE Transactions on Electron Devices, 2020, 67, 2182-2187.	3.0	5
10	Characterization of Pseudospark Discharge-Based Multigap Plasma Cathode Electron Source for the Generation of Short Pulsed Energetic Electron Beam. IEEE Transactions on Electron Devices, 2022, 69, 4572-4578.	3.0	1